

Notice of References Cited

Application/Control No.

10/045,542

Applicant(s)/Patent Under

Reexamination

DAS ET AL.

Examiner

Michael Barr

Art Unit

1762

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U.S. PATENT DOCUMENTS

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
X	A	US-6,028,012	02-2000	Wang, Xiewen	438/779
	B	US-			
	C	US-			
	D	US-			
	E	US-			
	F	US-			
	G	US-			
	H	US-			
	I	US-			
	J	US-			
	K	US-			
	L	US-			
	M	US-			

FOREIGN PATENT DOCUMENTS

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X	N	JP 2000-252461 A	09-2000	Japan	Arai et al.	-----
	O					
	P					
	Q					
	R					
	S					
	T					

NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
X	U	Xu et al., "Improved Performance and Reliability of N ₂ O Grown Oxynitride on 6H-SiC", IEEE ELECTRON DEVICE LETTERS, vol. 21. no. 6, June 2000, ppg. 298-300.
	V	
	W	
	X	

*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.